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PATENT

CEPPE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant

Yuji Okawa

Appl. No.

10/809,566

Filed

March 25, 2004

For

WAFER BACK SURFACE

TREATING METHOD AND DICING

SHEET ADHERING APPARATUS

Examiner

Thanhha S Pham

Group Art Unit

2813

CERTIFICATE OF MAILING

I hereby certify that this correspondence and all marked attachments are being deposited with the United States Postal Service as first-class mail in an envelope addressed to: Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450, on

January 12, 2006

(Date)

Katsuhiro Arai, Reg. No. 43,315

RESPONSE TO RESTRICTION REQUIREMENT

Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

Dear Sir:

This is in response to the communication from the Examiner mailed December 19, 2005. In response to the restriction requirement set forth in the communication, Applicant elects to prosecute Group I, Claims 1-10, drawn to a method of treating a wafer back surface. Applicant further elects Species 2 drawn to a wafer back surface treating with blowing ozone to which the claims shall be restricted if no generic claim is finally held to be allowable. Claims 1, 3, 6, and 8 read on the elected species, and claim 1 is generic. This election is made without traverse.

No fees are believed due for the present Amendment, however, should any fees be due, please charge them to our deposit account No. 11-1410.

Respectfully submitted,

KNOBBE, MARTENS, OLSON & BEAR, LLP

Dated: January 12, 2006 By:

Katsuhiro Arai

Registration No. 43,315 Attorney of Record Customer No. 20,995

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